

**CERTIFICATE OF MAILING BY "EXPRESS MAIL" (37 CFR 1.10)**

Applicant(s): ALI SHAKOURI ET AL.

Docket No.

UC01-161-2

Serial No.

10/039,290

Filing Date

January 4, 2002

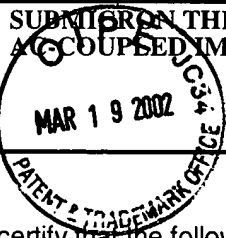
Examiner

Group Art Unit

2877

Invention: SUBMITTER THERMAL IMAGING METHOD AND ENHANCED RESOLUTION (SUPER-RESOLVED)  
AND COUPLED IMAGING FOR THERMAL INSPECTION OF INTEGRATED CIRCUITS

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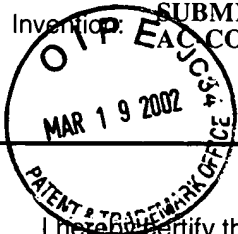

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